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APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.
10/647,985	08/26/2003	Patricia Beauregard Smith	TI-33260 3087	
23494 TEXAS INSTR	EXAM	EXAMINER		
P O BOX 6554	74, M/S 3999	EL ARINI, ZEINAB		
DALLAS, TX 75265			ART UNIT	PAPER NUMBER
			1792	
			NOTIFICATION DATE	DELIVERY MODE
			01/10/2008	ELECTRONIC

Please find below and/or attached an Office communication concerning this application or proceeding.

The time period for reply, if any, is set in the attached communication.

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		Application No.	Applicant(s)			
		10/647,985	SMITH ET AL.			
	Office Action Summary	Examiner	Art Unit			
		Zeinab E. EL-Arini	1792			
Period fo	The MAILING DATE of this communication appears on the cover sheet with the correspondence address Period for Reply					
A SH WHIC - Exter after - If NC - Failu Any	ORTENED STATUTORY PERIOD FOR REPLY CHEVER IS LONGER, FROM THE MAILING DANS IN INC. 19 PRIOR THE MAILING THE	ATE OF THIS COMMUNICATION 16(a). In no event, however, may a reply be tim fill apply and will expire SIX (6) MONTHS from a cause the application to become ABANDONE	I. sely filed the mailing date of this communication. Of (35 U.S.C. § 133).			
Status						
2a)⊠	<ol> <li>Responsive to communication(s) filed on <u>26 October 2007</u>.</li> <li>This action is <b>FINAL</b>. 2b) This action is non-final.</li> <li>Since this application is in condition for allowance except for formal matters, prosecution as to the merits is closed in accordance with the practice under <i>Ex parte Quayle</i>, 1935 C.D. 11, 453 O.G. 213.</li> </ol>					
Dispositi	on of Claims					
5) □ 6) ⊠ 7) □ 8) □ <b>Applicati</b> 9) □ 10) □	Claim(s) 1-6,8-15,17,18 and 20-23 is/are pendidal Of the above claim(s) is/are withdraw Claim(s) is/are allowed.  Claim(s) 1-6,8-15,17-18, and 20-23 is/are rejected to.  Claim(s) is/are objected to.  Claim(s) are subject to restriction and/or on Papers  The specification is objected to by the Examiner The drawing(s) filed on is/are: a) acceed Applicant may not request that any objection to the drawing sheet(s) including the correction of the oath or declaration is objected to by the Examiner The oath of the oat	ected.  election requirement.  epted or b) objected to by the Edrawing(s) be held in abeyance. See on is required if the drawing(s) is objected to by the drawing(s).	e 37 CFR 1.85(a). ected to. See 37 CFR 1.121(d).			
Priority u	ınder 35 U.S.C. § 119					
12) Acknowledgment is made of a claim for foreign priority under 35 U.S.C. § 119(a)-(d) or (f).  a) All b) Some * c) None of:  1. Certified copies of the priority documents have been received.  2. Certified copies of the priority documents have been received in Application No  3. Copies of the certified copies of the priority documents have been received in this National Stage application from the International Bureau (PCT Rule 17.2(a)).  * See the attached detailed Office action for a list of the certified copies not received.						
2) Notice 3) Inform	e of References Cited (PTO-892) e of Draftsperson's Patent Drawing Review (PTO-948) nation Disclosure Statement(s) (PTO/SB/08) r No(s)/Mail Date	4) Interview Summary Paper No(s)/Mail Da 5) Notice of Informal Pa 6) Other:	te			

## **DETAILED ACTION**

The amendment and remarks filed on 10/26/07 have been acknowledged and entered.

The rejection under 35 USC 102(b) as anticipated by Chang, stated in paper No. 20070620 has been withdrawn in view of applicants' amendment.

## Claim Rejections - 35 USC § 103

The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:

(a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as a whole would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negatived by the manner in which the invention was made.

Claims 1, 8-9, 11-12, 15, 18, and 21-23 are rejected under 35 U.S.C. 103(a) as being unpatentable over Chang (5,643,407).

Re. claims 1, 8, 21-23, Chang discloses a method of forming the intermetal dielectric layer of an integrated circuit. The reference teaches the patterning step (col. 2, line 45-col. 3, line 17), the wet cleaning step and the annealing step (col. 3, lines 18-37). Re. claims 9, 11, 12 and 21, see col. 3, lines 44-47, and claim 1, 5. Re. claim 15, it is inherent in the Chang process. Re. claim 18, see col. 2, lines 55-57.

Chang discloses the claimed invention except for the anneal duration as claimed. It would have been obvious to a person having ordinary skill in the art at the time the invention was made to adjust the anneal duration to obtain optimum results, since it has been held that discovering an optimum value of a result effective variable involves only routine skill in the art. *In re Boesch*, 617 F.2d 272, 205 USPQ 215 (CCPA 1980). See

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also *In re Aller*, 220 F.2d 454, 105 USPQ 223 (CCPA 1955). This is also because the time for annealing depends on the amount of moisture to be removed from the surface.

1. Claims 5-6 and 17 are rejected under 35 U.S.C. 103(a) as being unpatentable over Chang' 407 in combination with Nguyen et al. (2003/0104320).

Chang' 407 as discussed supra does not teach dry cleaning (using plasma) before cleaning the polymer residue.

Nguyen et al. disclose that the conventional photoresist removal sequence typically consists of combination of a dry strip process using oxygen to remove the bulk of the photoresist layer and a wet clean process to remove the residues and metal contaminants, and the conventional sequence further includes an anneal step to remove any moisture resulting from the wet strip. See paragraph 7.

It would have been obvious for one skilled in the art to use the plasma cleaning before the wet cleaning in Chang' 407 process, because it is well known in the conventional photoresist removal sequence. Re. claim 17, the metal deposit in Chang' 407 may include copper.

2. Claims 2-4, 10, and 13-14 are rejected under 35 U.S.C. 103(a) as being unpatentable over Chang' 407 in combination with Nguyen et al. (2003/0104320) as applied to claims 5-6 and 17 above, and further in view of Chang et al. (2003/0008518), Chiu et al. (6,107,202), and Akino et al. (6,417,108).

Re. claim 2, see Chang et al, claims 4 and 14.

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Re. claim 4, see Chiu et al, col. 8, last line.

Re. claim 10, one skilled in the art would adjust the anneal temperature to obtain optimum results. Re. claims 13 and 14, one skilled in the art would adjust the time to obtain optimum results. This is also because the time for annealing depends on the amount of moisture to be removed from the surface.

It would have been obvious to a person having ordinary skill in the art at the time the invention was made to adjust the anneal duration and temperature to obtain optimum results, since it has been held that discovering an optimum value of a result effective variable involves only routine skill in the art. *In re Boesch*, 617 F.2d 272, 205 USPQ 215 (CCPA 1980). See also *In re Aller*, 220 F.2d 454, 105 USPQ 223 (CCPA 1955).

Re claim 3, it is well known in the art to use acid in wet cleaning wafer. See Akino et al., col. 6, lines 30-31.

It would have been obvious for one skilled in the art to use the solvent taught by Chiu et al. and the acid taught by Akino et al. in the Chang' 407 process to improve the cleaning process. One skilled in the art would use the dielectric layer taught by Chang et al' 518 in the Chang' 407 process because the dielectric layer in both references are equivalent.

3. Claim 20 is rejected under 35 U.S.C. 103(a) as being unpatentable over Smith et al. (2002/0058397).

Smith et al. teach a method of fabricating an electronic device. The reference discloses performing plasma strip, wet cleaning, low pressure anneal, fluorine based

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solvent as claimed. See claims 1-5, 30-31, and paragraph 24, lines 12-15. The acid, see pages 25 and 27.

The reference does not teach the temperature, and the anneal duration as claimed.

It would have been obvious for one skilled in the art to use the process taught by Smith et al. to remove volatile cleaner compounds from a post-etch substrate as claimed. This is because it would have been obvious to a person having ordinary skill in the art at the time the invention was made to adjust the anneal duration and temperature to obtain optimum results and to improve the cleaning process, since it has been held that discovering an optimum value of a result effective variable involves only routine skill in the art. *In re Boesch*, 617 F.2d 272, 205 USPQ 215 (CCPA 1980). See also *In re Aller*, 220 F.2d 454, 105 USPQ 223 (CCPA 1955).

## Response to Arguments

4. Applicant's arguments with respect to claims 1-6, 8-15, 17-18, and 20-23 have been considered but are moot in view of the new ground(s) of rejection, and for the reason set forth in this office action.

## Conclusion

Applicant's amendment necessitated the new ground(s) of rejection presented in this Office action. Accordingly, **THIS ACTION IS MADE FINAL**. See MPEP § 706.07(a). Applicant is reminded of the extension of time policy as set forth in 37 CFR 1.136(a).

A shortened statutory period for reply to this final action is set to expire THREE MONTHS from the mailing date of this action. In the event a first reply is filed within TWO MONTHS of the mailing date of this final action and the advisory action is not mailed until after the end of the THREE-MONTH shortened statutory period, then the shortened statutory period will expire on the date the advisory action is mailed, and any

extension fee pursuant to 37 CFR 1.136(a) will be calculated from the mailing date of the advisory action. In no event, however, will the statutory period for reply expire later than SIX MONTHS from the date of this final action.

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Zeinab E. EL-Arini whose telephone number is 571-272-1301. The examiner can normally be reached on Monday.-Friday.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Michael Barr can be reached on 571-272-1414. The fax phone number for the organization where this application or proceeding is assigned is 571-273-8300.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free). If you would like assistance from a USPTO Customer Service Representative or access to the automated information system, call 800-786-9199 (IN USA OR CANADA) or 571-272-1000.

Zeinab E EL-Arini Primary Examiner Art Unit 1792

ZEE 12/26/07